

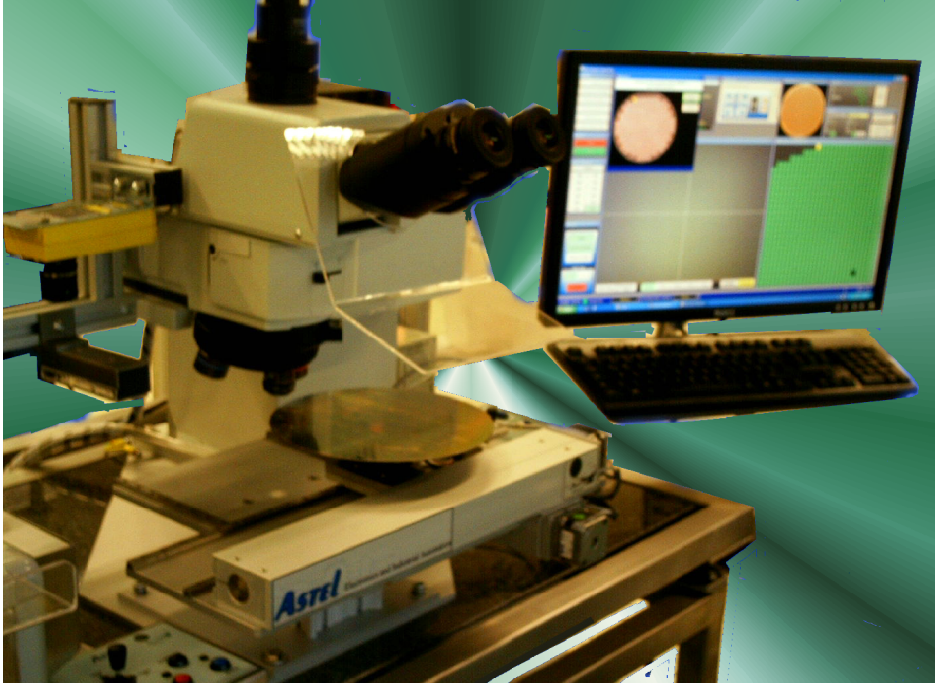
# Semicon Synapsis

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# SemiMAP

Map driven wafer inspection system



# SemiMAP Wafer inspection system

The new SemiMAP system is an extremely powerful inspection system for wafers.

It features a special motorized X/Y/R precision stage which can be mounted on semiconductor inspection microscopes, an image acquisition system and a powerful inspection software.

It is possible to identify and download wafer maps, inspect wafer dies and modify each die BINCODE, take and store pictures, take measures with 1 $\mu$  resolution, scan wafers and much more.

The system is modular, and can be interfaced with microscope loaders or macro inspection loaders, and can include as option the OCR wafer ID reader.

System is SEMI compliant for map types and can be customized on request.

Specifications	
Stage	Motorized, X,Y and R, resolution <1 $\mu$ and <0.01° (depending on version)
Control	PC based controller, 4 step motor axis - microstep mode
Image acquisition	USB devices - high resolution mode from 2 Mpix up
Monitor	High resolution 22" wide screen LCD monitor
Type of inspection	Single die random access, sequential scan, manual, BINCODE modify
Map type	According to SEMI standard, plus multiple embedded maps
Map download/upload	TCP/IP, local mode, local mode with wafer template (read only)
Wafer centering	With centering pins (manual) - through loader (automatic)
Compatible microscopes	Astel MX-R - Other semiconductor inspection microscopes
Autofocus management	For step motor driven Z axis - auto mode or FOCUS button
Measurement function	With crosshair on screen, resolution 1 $\mu$ (X,Y and Z)
Optional ID reader	Cognex DVT with LED illuminator
Facilities	AC 220 - 240 V - 3,5 A 50 /60 Hz Vacuum - 60 to -90 KPa - 10 l/min Compressed air - 6 bar

(Specifications are subject to change without any obligation on the part of manufacturer)

